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Paper No. 8

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In Re Application of
YOSHIROU TSURUGIDA
Application No. 10/034,379
Filed: January 3, 2002
Title: METHOD FOR SELECTIVELY OXIDIZING A SILICON
WAFER

Withdrawal From Issue

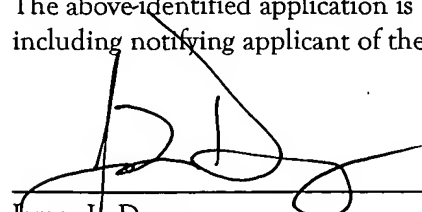
The above-identified application is withdrawn from issue after payment of the issue fee due to unpatentability of one or more claims. See 37 CFR 1.313(b).

The above-identified application is hereby withdrawn from issue.

The issue fee is refundable upon written request. If, however, the application is again found allowable, the issue fee can be applied toward payment of the issue fee in the amount identified on the new Notice of Allowance and Issue Fee Due upon written request. This request and any balance due must be received on or before the due date noted in the new Notice of Allowance in order to prevent abandonment of the application.

Telephone inquiries should be directed to David Nelms at (703) 308-4910.

The above-identified application is being forwarded to the examiner for prompt appropriate action, including notifying applicant of the new status of this application.


James L. Dwyer
Director, Technology Center 2800
Communications